



PATENT APPLICATION

#57705  
D.King  
2/27/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Satoshi TAKANO

Application No.: 09/819,690

Filed: March 29, 2001

Docket No.: 109107

For: SEMICONDUCTOR MANUFACTURING METHOD, SUBSTRATE PROCESSING  
METHOD, AND SEMICONDUCTOR MANUFACTURING APPARATUS

INFORMATION DISCLOSURE STATEMENT

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of the non-English language reference numbers JP A 5-304273 and JP A 6-104178 is discussed in the present specification.
- ☒ 3. English-language Abstracts of the non-English language references JP A06-104178 and JP 2000-150815 are attached hereto.
- ☒ 4. JP A 5-304273 corresponds to US 2,508,948

Respectfully submitted,

James A. Oliff

Registration No. 27,075

Thomas J. Pardini

Registration No. 30,411

JAO:TJP/cln

Date: June 15, 2001

OLIFF & BERRIDGE, PLC  
P.O. Box 19928  
Alexandria, Virginia 22320  
Telephone: (703) 836-6400

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